

Development of Low-Temperature Bonding Method and Application to Micro/Nano Chemical Systems

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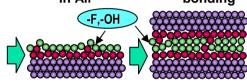
A new method is developed for low-temperature bonding which requires no thermal treatment on the bonding process. The method is useful for integration and packaging of micro/nano chemical systems for realizing novel chemical devices as well as MEMS/NEMS devices.

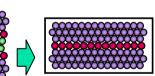
Surface activated bonding (SAB) method for low temperature bonding

Water adsorption Room Temperature Annealing 200~400°C in Air bonding

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Vacuum chamber

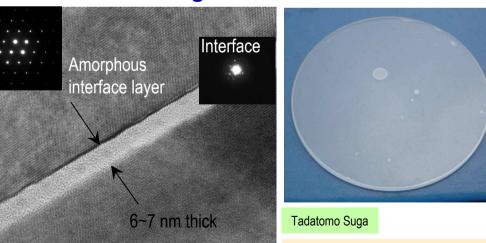




Quartz/Quartz Bondin

M. M. R. Howlader, S. Suehara, T. Suga, Sensors and Actuators A 127 (2006) 31–36 SAB method

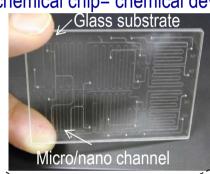
Si/Si bonding



5 nm

Micro/nano chemical system (Laboratory on a chip)

Microchemical chip= chemical device





Basic science in micro/nano space Applications (medical, energy, etc.)

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T.Tsukahara et al., *Chem.Soc.Rev.*, *39*, *1000* (2010). **DOI**: 10.1039/B822557P